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Inventor: **H. Montgomery Manning**

OCT 18 2005

Title: **Methods of Forming Capacitor Devices**

Assignee: **Micron Technology, Inc.**

Serial No.: **10/733,181**

Filed: **December 10, 2003**

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

PURSUANT TO 37 C.F.R. §§ 1.56, 1.97 AND 1.98

The attached Form PTO-1449 is submitted in compliance with 37 CFR §1.56. Pursuant to FEDERAL REGISTER, Vol. 69, No. 182, pg. 56542 (September 21, 2004), no copies of any cited U.S. patents or U.S. published applications are included herewith. Copies of all other cited art are attached. No admission is made regarding whether the listed references are prior art.

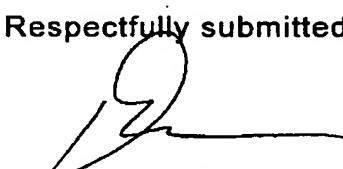
This Supplemental Information Disclosure Statement is being filed before the mailing of a first Office Action on the merits. Therefore, no fee is believed to be required. However, in the event that a fee is required for filing this Supplemental Information Disclosure Statement, please charge the fee specified under 37 C.F.R. § 1.17(p) to Deposit Account No. 23-0925.

Citation of these references is respectfully requested.

Respectfully submitted,

Dated: 10/18/05

By:


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Sheet 1 of 1

Form PTO-1449 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2295	SERIAL NO. 10/733,181
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)		APPLICANT Micron Technology, Inc.	
		FILING DATE December 10, 2003	GROUP 2812

U.S. PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	2001/0012223	08/01	Kohyama			
	AB	2002/0030221	03/02	Sandhu et al.			
	AC	2002/0098654	07/02	Durcan et al.			
	AD	2002/0153614	10/02	Ema et al.			
	AE	2003/0178684	09/03	Nakamura			
	AF						
	AG						
	AH						
	AI						

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Sub-class	Translation	
							Yes	No
	AJ	2004/027898	08/04	PCT Search Report				
	AK	2004/040252	12/04	PCT Search Report				
	AL							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

	AM	Kim, D.H. et al., "A Mechanically Enhanced Storage Node for Virtually Unlimited Height (MESH)" Capacitor Aiming at Sub 70nm DRAMs", IEEE Jan. 2004, pp. 69-72.
EXAMINER	DATE CONSIDERED	

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.